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12/06/01

PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

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|----------|-------------|-------|----------|------|-------------|
| APPL NUM | FILING DATE | CLASS | SUBCLASS | GAU | EXAMINER |
| 10003287 | 12/06/2001 | 433 | | 3912 | Long, J. A. |

**APPLICANTS: Kang Sang;

**CONTINUING DATA VERIFIED:

SPM NONE

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** FOREIGN APPLICATIONS VERIFIED:

REPUBLIC OF KOREA 2001-54510 09/05/2001

SKM

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|--|---|----------------------------------|
| PG-PUB | DO NOT PUBLISH <input type="checkbox"/> | RESCIND <input type="checkbox"/> |
| Foreign priority claimed | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no | ATTORNEY DOCKET NO |
| 35 USC 119 conditions met | <input checked="" type="checkbox"/> yes <input type="checkbox"/> no | 10729-P67237US0 |
| Verified and Acknowledged Examiners's initials | SKM SKM | |
| TITLE : Method of fabricating an exposure mask for semiconductor manufacture | | |
| U.S. DEPT. OF COMM./PAT. & TM-PTO-436L (Rev. 12-94) | | |

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|--|-----------|---|--------------|
| NOTICE OF ALLOWANCE MAILED | | CLAIMS ALLOWED | |
| | | Total Claims <input type="checkbox"/> Print Claim for: O.G. | |
| | | DRAWING | |
| | | Sheets Drawg. | Fig.s Drawg. |
| | | Print Fig. | |
| ISSUE FEE | | Primary Examiner | |
| Amount Due | Date Paid | PREPARED FOR ISSUE | |
| TERMINAL | | Application Examiner | |
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